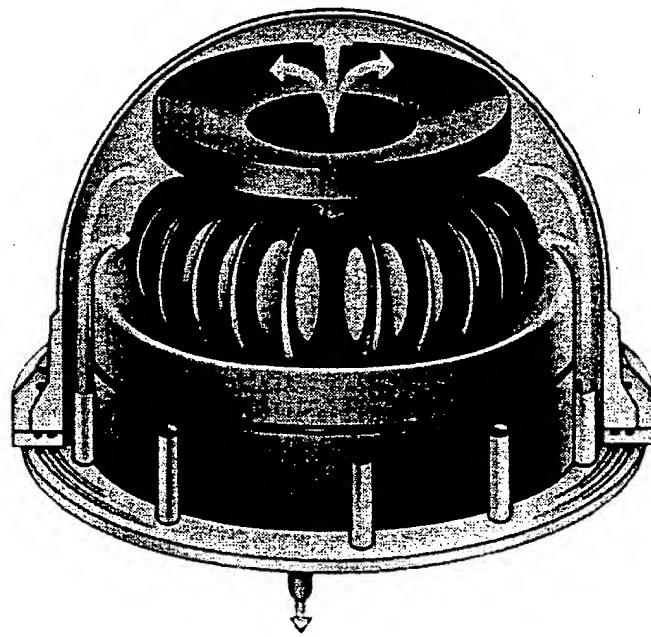


HANDBOOK OF THIN-FILM DEPOSITION PROCESSES AND TECHNIQUES

Principles, Methods, Equipment
and Applications



Edited by
Klaus K. Schuegraf

NOYES PUBLICATIONS

Appendix B

Goldwasser *et al.*
Application No.: 08/847,967

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